method film formation apparatus. There were wrinkles in the substrate during film formation with the parallel plate method film formation apparatus, and therefore the film thickness distribution was on the order of ±10% and color unevennesses could be observed even with the naked eye. There were no wrinkles in the substrate during film formation with the curved surface roller method film formation apparatus, the film thickness distribution could be suppressed to approximately ±5%, and almost no color unevennesses could be verified by observing with the naked eye. As a result, it can be said that film thickness unevennesses can be suppressed.

In the Claims:

Please amend claims 1 and 3 as follows.

- 1. (Amended) A film formation apparatus for a flexible substrate, said film formation apparatus comprising:
 - at least two rollers for continuously conveying the flexible substrate from one end to the other end;
- a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
- a ground electrode in contact with each of the plurality of cylindrical rollers;

an opposing electrode opposing the ground electrode;

a vacuum chamber;

an introducing means for introducing a gas into the vacuum chamber;

a gas evacuation means; and

an energy supplying means for supplying an energy to make a plasma from the gas;

wherein the flexible substrate is located between the ground electrode and the opposing electrode,

wherein center axes of the plurality of cylindrical rollers run parallel to each other,

wherein the substrate is in contact with each of the plurality of cylindrical rollers,

wherein the ground electrode act as a conveyance supporting portion,

wherein each of the plurality of cylindrical rollers is a heater.

3. (Amended) A film formation apparatus for a flexible substrate, said film formation apparatus comprising:

at least two rollers for continuously conveying the flexible substrate from one end to the other end;

a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;

a ground electrode in contact with each of the plurality of cylindrical rollers;

an opposing electrode opposing the ground electrode, wherein the flexible substrate is located between the ground electrode and the opposing electrode,

wherein center axes of the plurality of cylindrical rollers run parallel to each other,

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wherein the substrate is in contact with each of the plurality of cylindrical rollers,

wherein the ground electrode act as a conveyance supporting portion,

wherein each of the plurality of cylindrical rollers is a heater.

Please add the following new claims 8 and 9.

8. An apparatus according to claim 1, wherein the film formation apparatus is a plasma CVD apparatus.



9. An apparatus according to claim 1, wherein the energy is an electromagnetic wave.